119TH CONGRESS H.R.
To amend section 172 of the Clean Air Act to support critical manufacturing, and for other purposes.
IN THE HOUSE OF REPRESENTATIVES
M introduced the following bill; which was referred to the Committee on
A BILL To amend section 172 of the Clean Air Act to support critical manufacturing, and for other purposes.
1 Be it enacted by the Senate and House of Representa-
2 tives of the United States of America in Congress assembled,
3 SECTION 1. SHORT TITLE.
4 This Act may be cited as the "Air Permitting Im-
5 provements to Protect National Security Act of 2025".
6 SEC. 2. SUPPORTING CRITICAL MANUFACTURING.
7 Section 172 of the Clean Air Act (42 U.S.C. 7503)
8 is amended by inserting after subsection (e) the following:

"(f) ALTERNATIVE REQUIREMENTS FOR CRITICAL

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10 Manufacturing.—

1	"(1) National Security Waiver.—Upon ap-
2	plication by the owner or operator of a proposed new
3	or modified advanced manufacturing facility or crit-
4	ical mineral facility located in a nonattainment area,
5	the President may determine that, based on the na-
6	tional security interests of the United States, such
7	a facility is exempt from the requirements of this
8	subchapter to offset increased emissions of any air
9	pollutant. Such determination shall not be delegable
10	by the President to any other person.
11	"(2) ALTERNATIVE MEANS OF COMPLIANCE.—
12	Notwithstanding any other provision of this Act, the
13	permitting authority of a State shall allow the owner
14	or operator of a proposed new or modified advanced
15	manufacturing facility or critical mineral facility to
16	offset by alternative or innovative means expected
17	emissions increases under the following conditions:
18	"(A) The advanced manufacturing facility
19	or critical mineral facility demonstrates that it
20	has used all reasonable means to obtain and
21	utilize offsets for the emission increases beyond
22	allowable levels, that all available offsets are
23	being used by other sources, and that sufficient
24	offsets are not available to the source.

1	"(B) The advanced manufacturing facility
2	or critical mineral facility complies with an al-
3	ternative offset measure, established by the per-
4	mitting authority, designed to offset any emis-
5	sion increases beyond permitted levels not di-
6	rectly offset by the source. In lieu of imposing
7	any alternative offset measures, the permitting
8	authority may impose an emissions fee to be
9	paid to such authority of a State which shall be
10	an amount no greater than 1.5 times the aver-
11	age cost of stationary source control measures
12	adopted in the area during the previous 3 years.
13	The permitting authority shall utilize the fees
14	in a manner that maximizes the emissions re-
15	ductions in that area.
16	"(3) Definitions.—In this subsection:
17	"(A) ADVANCED MANUFACTURING FACIL-
18	ITY.—The term 'advanced manufacturing facil-
19	ity' means a facility for which the primary pur-
20	pose is the manufacturing of semiconductors or
21	semiconductor manufacturing equipment.
22	"(B) CRITICAL MINERAL FACILITY.—The
23	term 'critical mineral facility' means a facility
24	for which the primary purpose is the extraction,
25	processing, refining, or milling of a critical min-

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- 2 rior.".